

INSPECTION METHOD AND DEVICE MANUFACTURING METHOD

ABSTRACT OF THE DISCLOSURE

A method according to one embodiment of the invention may be
5 applied to enhance scatterometry measurements made from a two-component
test pattern. Reference patterns corresponding to each of the components of
the two-component pattern are also printed. Scatterometry signals derived
from the reference patterns, corresponding to the separate components of the
test pattern, are used to enhance the signal from the test pattern to improve
10 sensitivity and signal-to-noise ratios.